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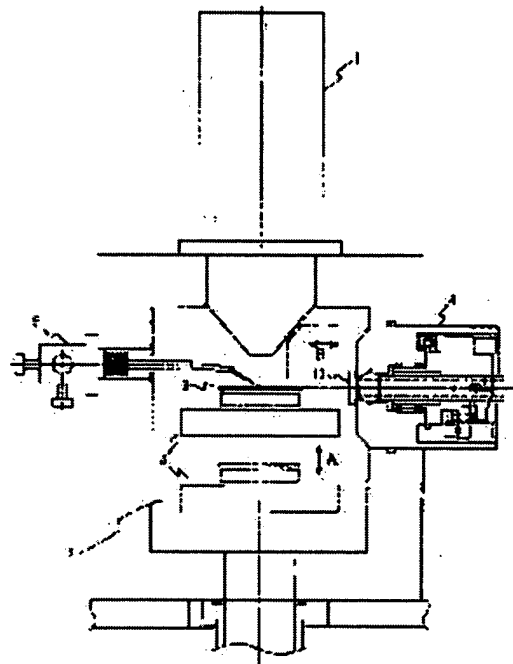
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(54) SAMPLE PREPARING DEVICE FOR FIB SAMPLE

(57)Abstract:

PROBLEM TO BE SOLVED: To enhance operation, workability of sample preparation for TEM observation and to facilitate additional working.

SOLUTION: This preparation device for an FIB sample locally cuts out a observation target part of a wafer 3 with a focused ion beam, and works in a sample 12 observable with a transmission electron microscope, and has a sample stage 4 for the wafer for placing the wafer 3 and locally cutting out the observation target part; a TEM sample stage 6 for mounting the cut out sample 2 and working in the sample observable with the transmission electron microscope; and a manipulator 5 for gripping out the sample cut out with the sample stage 4 for the wafer and fixing it to the TEM sample stage 6, within an FIB sample chamber 2. The sample stage 4 for the wafer and the TEM sample stage 6 have a moving mechanism movable to the FIB working position without interference of mutual staged.



LEGAL STATUS

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